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**LIST OF PRIOR ART CITED BY APPLICANT**  
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To Be AssignedApplicant  
Kristina Vogt et alFiling Date  
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Group

**U.S. PATENT DOCUMENTS**

EXAMINER INITIAL	DOCUMENT NUMBER	DATE	NAME	CLASS	SUBCLASS	FILING DATE IF APPROPRIATE
	AA					
	AB					
	AC					
	AD					
	AE					
	AF					
	AG					
	AH					
	AI					
	AJ					
	AK					

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09/998560  
11/29/01

**FOREIGN PATENT DOCUMENTS**

		DOCUMENT NUMBER	DATE	COUNTRY	CLASS	SUBCLASS	TRANSLATION	
							Yes	No*
	AL	00/00567	01/06/2000	World Patent				
	AM	00/24842	05/04/2000	World Patent				
	AN	99/64527	12/16/99	World Patent				
	AO	99/47618	09/23/99	World Patent				
	AP	99/67056	12/29/99	World Patent				

**OTHER PRIOR ART** (Including Author, Title, Date, Pertinent Pages, Etc.)

	AR	Microchip Fabrication: A Practical Guide to Semiconductor Processing, Peter Van Zant ed., McGraw-Hill (month unavailable) 2000, pages 302-309 & 401-403
	AS	Copper CMP: A Quistion of Tradeoffs, Peter Singer, Semiconductor International, Verlag Cahner, May 2000, pages 73-84
	AT	Chemical Mechanical Planarization of Microelectronic Material, J.M. Steigerwald, S.P. Murarka & R.J. Gutmann, John Wiley & Sons, Inc. (month unavailable) 1997, CMP Variable and Manipulations, pages 42-43

EXAMINER	DATE CONSIDERED
EXAMINER Initial if referenced considered, whether or not citation is in conformance with MPEP 609: Draw line through if not in conformance and not considered. Include copy of this form with next communication to applicant.	

\* Neither English Language Equivalent nor an English Language Translation is available.